

OPERATION METHOD OF ION SOURCE AND ION BEAM IRRADIATION APPARATUS

ABSTRACT OF THE DISCLOSURE

This ion source 2 has the heating furnace 4 for heating a solid material 6 to produce a vapor 8, the plasma production vessel 16 for producing a plasma 24 by ionizing this vapor 8, and the vapor conduit tube 10 connecting both the heating furnace 4 and the plasma production vessel 16. In this ion source 2, using indium fluoride 6a as the solid material 6, an ion beam 30 containing indium ions is led out, while the temperature of the heating furnace 4 is kept in a range from 450° to 1170°C, and below the temperature of the plasma production vessel 16.

Figure 1



162162



G00002